

EV317135699**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. 09/677,478
Filing Date October 2, 2000
Inventor Guy T. Blalock et al.
Assignee Micron Technology, Inc.
Group Art Unit 1765
Examiner L. Vinh
Attorney's Docket No. MI22-1544
Title: Plasma Etching Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT


References – See Attached Form PTO-1449

The Examiner's attention is directed to the references listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether the submitted references are prior art.

Citation of the referenced art is respectfully requested.

Respectfully submitted,

Dated: 6-30-03

By: 
D. Brent Kenady
Reg. No. 40,045

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1724		SERIAL NO. 09807375	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary.)				APPLICANT Blalock et al.			
				FILING DATE October 2, 2000		GROUP 1765	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
	AA	6,330,953 B1	03/18/03	Allen, III			
	AB	5,366,333	02/09/99	Chen et al.			
	AC	5,355,938	02/02/99	Peters et al.			
	AD	5,343,847	12/01/98	Pu et al.			
	AE	5,026,666	06/25/91	Hills et al.			
	AF	6,434,327 B1	08/13/02	Groen et al.			
	AG						
	AH						
	AI						
	AJ						
	AK						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AL						
	AM						
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR		Stanley Wolf and Richard Tauber. Silicon Processing for the VLSI Era, Vol. 1, pp 549, 1986.				
	AS						
	AT						
EXAMINER				DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							